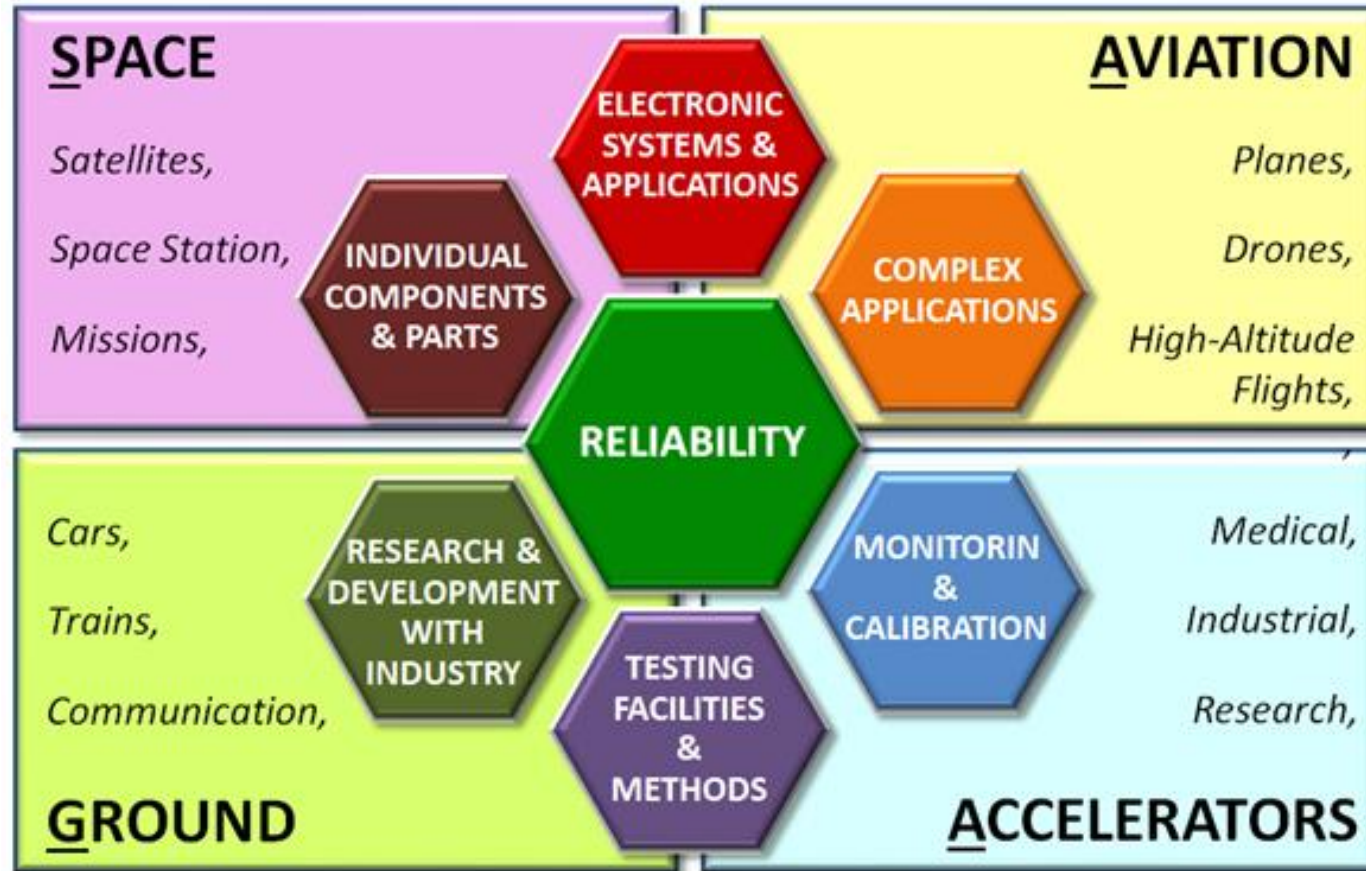


An Introduction to Radiation Effects on Electronics

Rémi Gaillard
Consultant



Reliability and Radiation Effects (RADSAGA)



Radiation Effects on Electronics

A Mature Field of research and applications

- NSREC 2017
- Basic Mechanisms of Radiation Effects
- Radiation Effects in Devices and ICs
- Single-Event Effects: Devices and ICs
- Hardness Assurance
- Space and Terrestrial Environments
- Hardening by Design
- Single-Event Effects: Mechanisms and Modeling
- Single-Event Effects: Transient Characterization
- Photonic Devices and Integrated Circuits
- Dosimetry

Data workshop



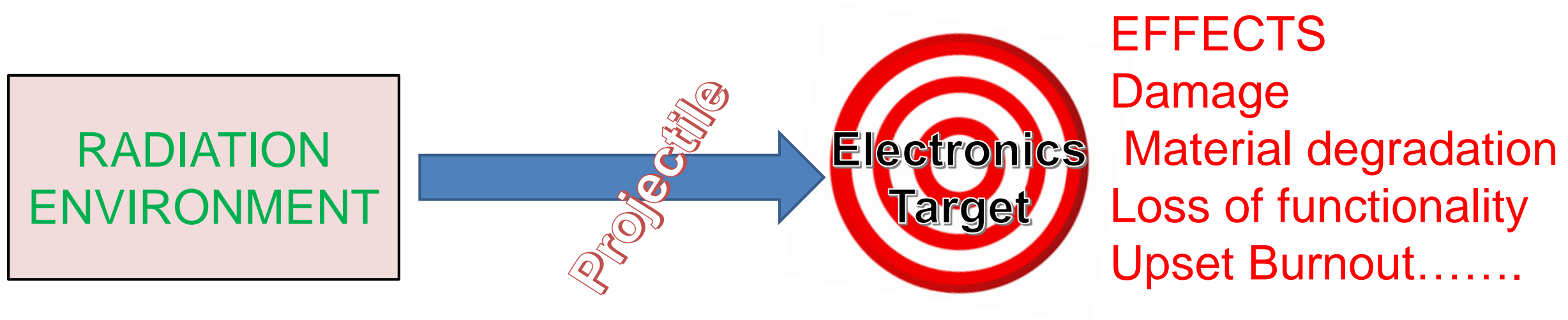
- RADECS2017
- Basic Mechanisms of Radiation Effects
- Radiation Effects in Devices and ICs,
- Single Event Effects in Devices and ICs
- Radiation Hardness Assurance at Device and System Level
- Radiation Environments (Space, Atmospheric, Terrestrial and [Accelerators](#))
- Hardening by Design
- Single Event Effects Mechanisms and Modelling
- Single Event Transients and Laser testing
- Radiation Effects in Optoelectronics and optical fibers
- [Facilities](#) and Dosimetry
- [Analog and Mixed-Signal Integrated Circuits for use in Radiation Environments](#)
- [Radiation Effects on Materials](#)
- [In-Orbit Low-Cost Radiation Studies \(Nanosat, Stratobus ...\)](#)

Data workshop

Radiation Effects on Electronics

The interaction of two complex universes

How to enter in this world?



4

Radiation environment: What, Where, How much, Energy, Flux of particles

Charged particles
Electrons,
Muons
Protons
alphas
Heavy Ions

Neutral
Neutrons
Photons

Energy
eV,
keV
MeV
GeV
TeV

Velocity

Rest
Mass

Lifetime

Flux, Energy Incidence

Particles/(cm²*s)
Mean, variability
Burst duration
Duty cycle

Fermions Bosons

Leptons Hadrons Gluons

Radiation: charge, mass, interaction mode

- Example: $E=1\text{ MeV}$ alpha, proton, electron, photon, neutron

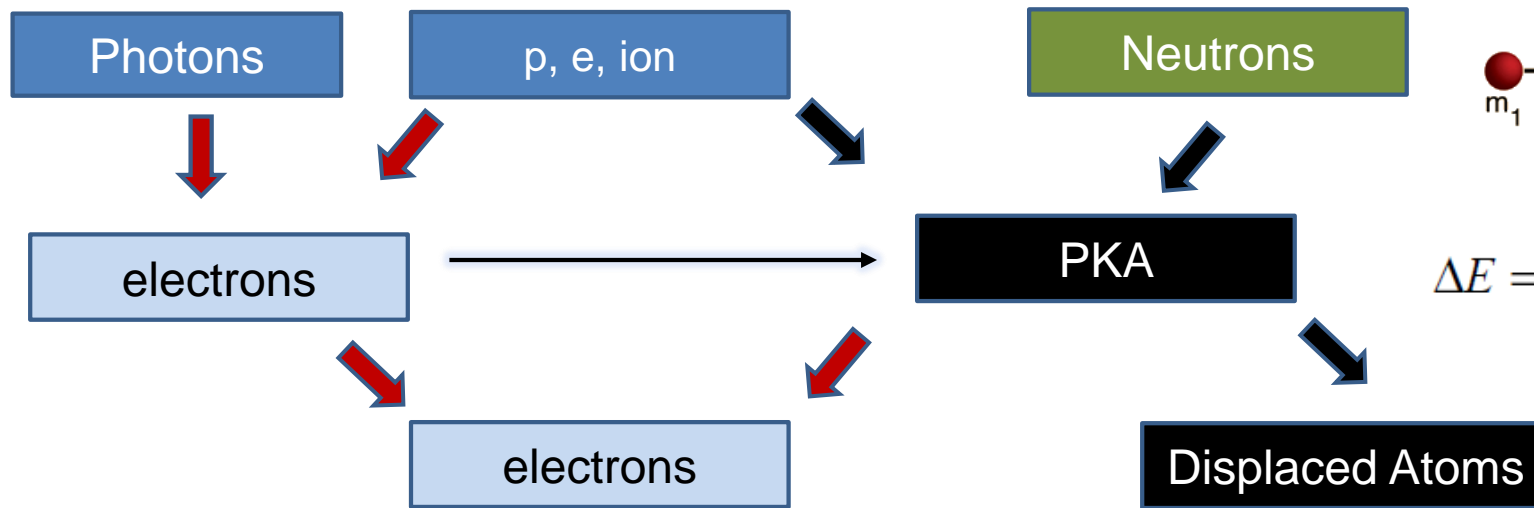
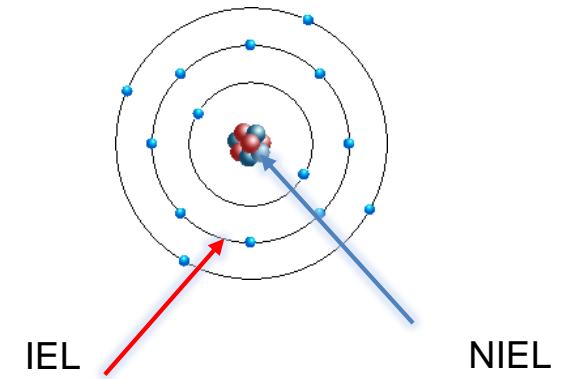
Characteristic	Radiation ($E_K = 1\text{ MeV}$)				
	Alpha (α)	Proton (p)	Beta (β) or Electron (e)	Photon (γ or X ray)	Neutron (n)
Symbol	${}^4_2\alpha$ or He^{2+}	1_1p or H^{1+}	${}^0_{-1}e$ or β	${}^0_0\gamma$	1_0n
Charge	+2	+1	-1	neutral	neutral
Ionization	Direct	Direct	Direct	Indirect	Indirect
Mass (amu)	4.001506	1.007276	0.00054858	—	1.008665
Velocity (cm/sec)	6.944×10^8	1.38×10^9	2.82×10^{10}	$c = 2.998 \times 10^{10}$	1.38×10^9
Speed of Light	2.3%	4.6%	94.1%	100%	4.6%
Range in Air	0.56 cm	1.81 cm	319 cm	82,000 cm*	39,250 cm*

* range based on a 99.9% reduction

IEL and NIEL

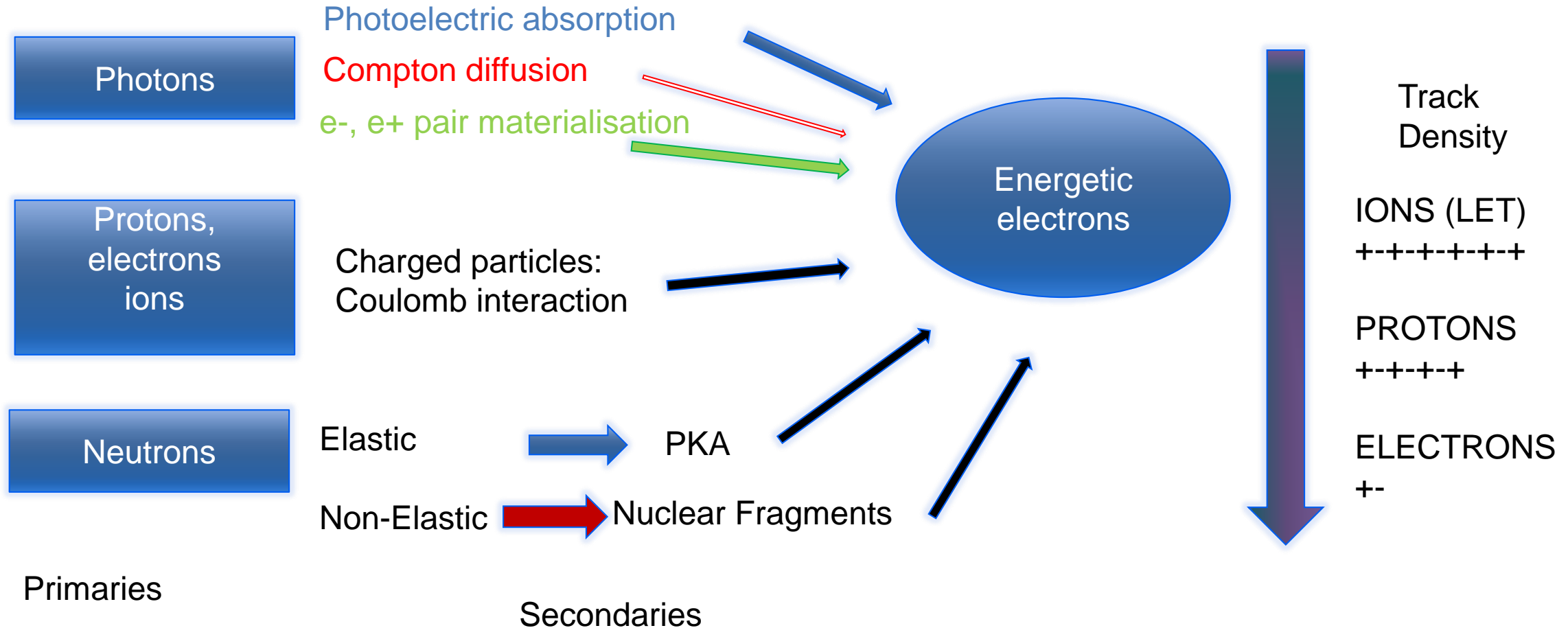
IEL: electron interaction from primary knock-on electron (PKE) to electron-hole pairs

NIEL: from PKA (Primary Knock on Atom) to stable defects



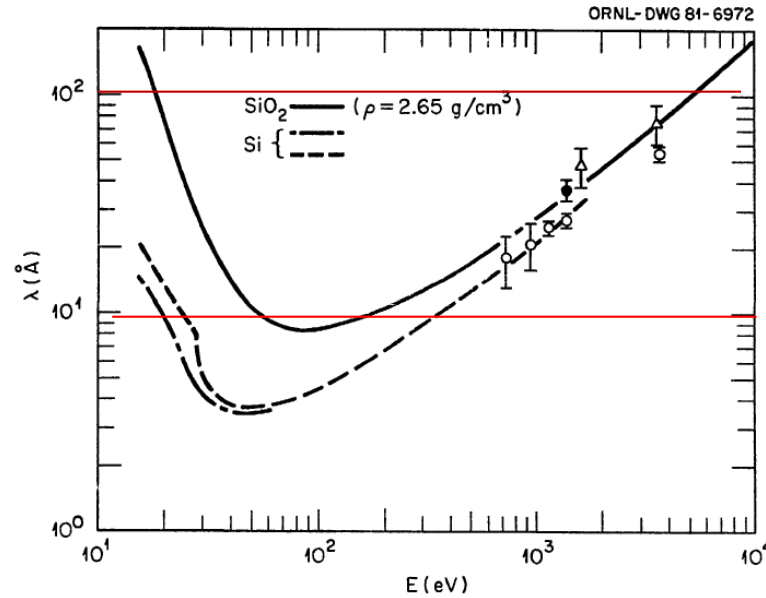
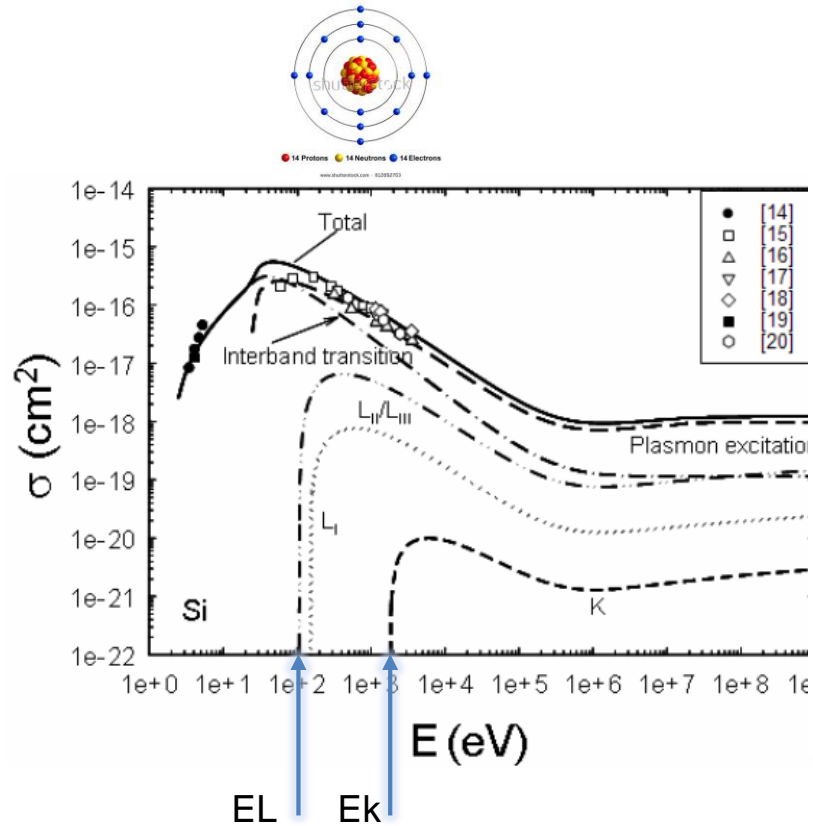
$$\Delta E = 4 \frac{m_p M_{Si}}{(m_p + M_{Si})^2} \sin^2\left(\frac{\vartheta}{2}\right) \cdot E_p$$

IEL Mechanism: creation of Energetic Electrons

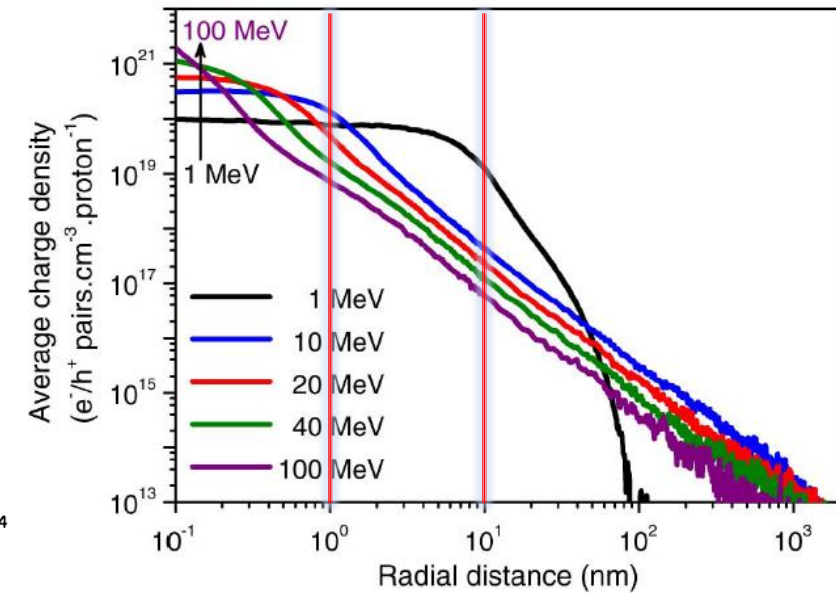


IEL: Interaction, propagation, thermalisation

- Cross section of electrons in silicon

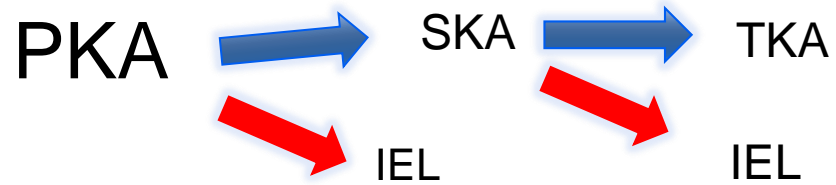


From: Ashley NS 1976



From: M. Raine et al. NS vol61 N°4 2014

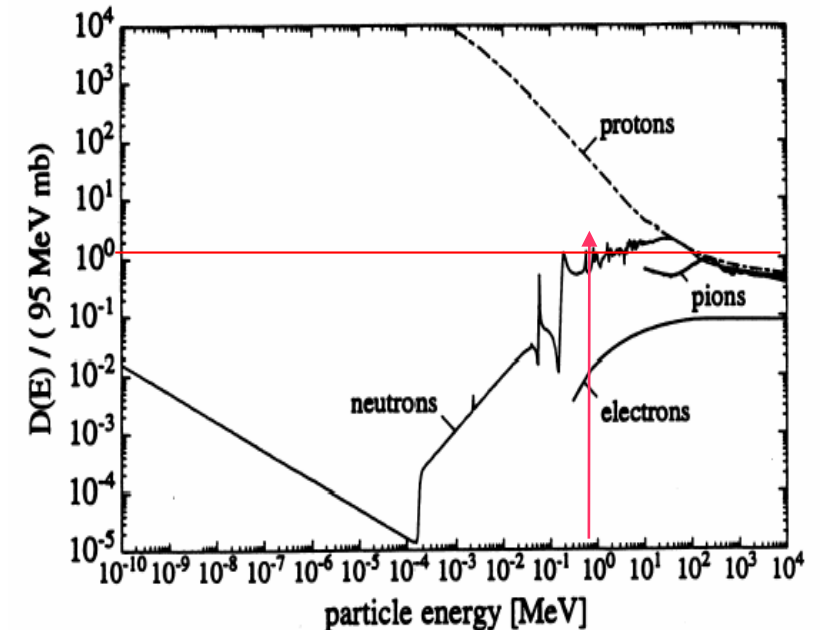
NIEL: Non Ionizing Energy Loss



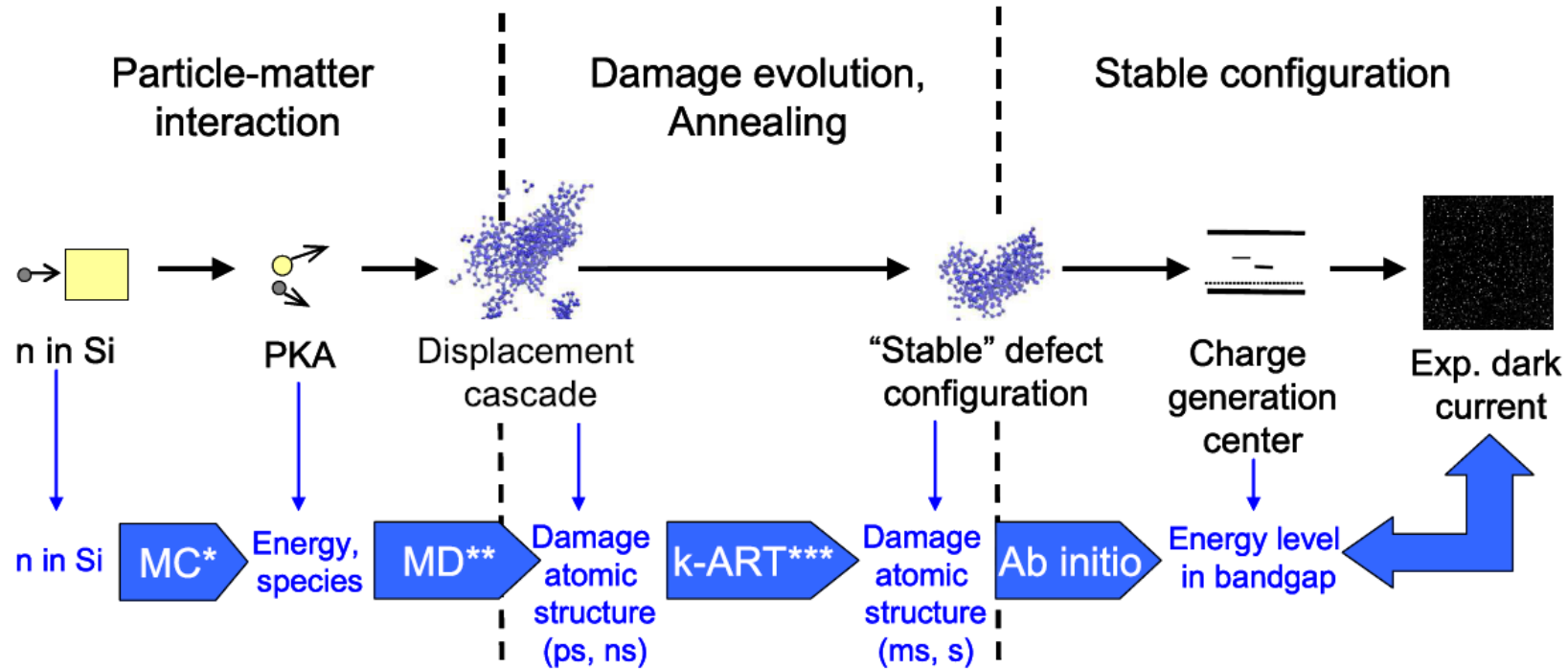
NIEL Factor: Product of cross-section of interaction by mean NIEL energy released in each interaction:

1 MeV neutron → 95MeV*mbarn per atom
(1mbarn= 1 E-27 cm²)

- NIEL Relative Energy Loss



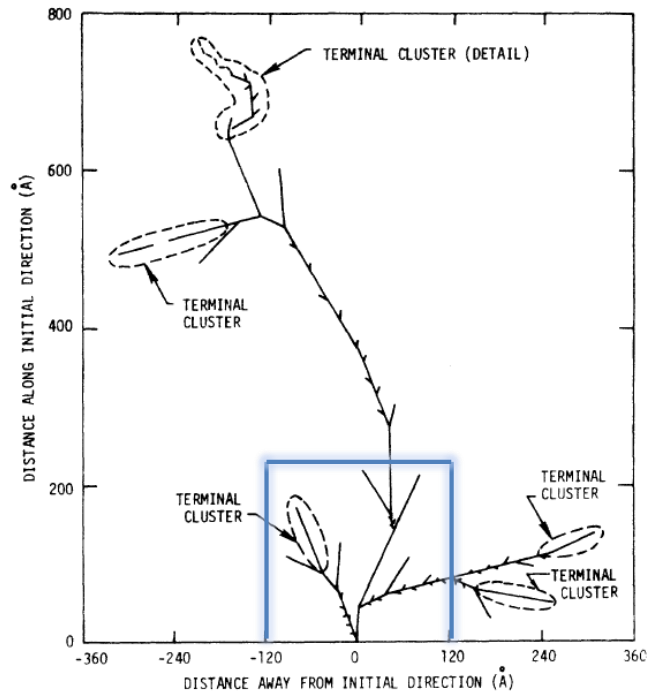
Global approach of Displacement Damage Analysis: Successive steps and associated tools



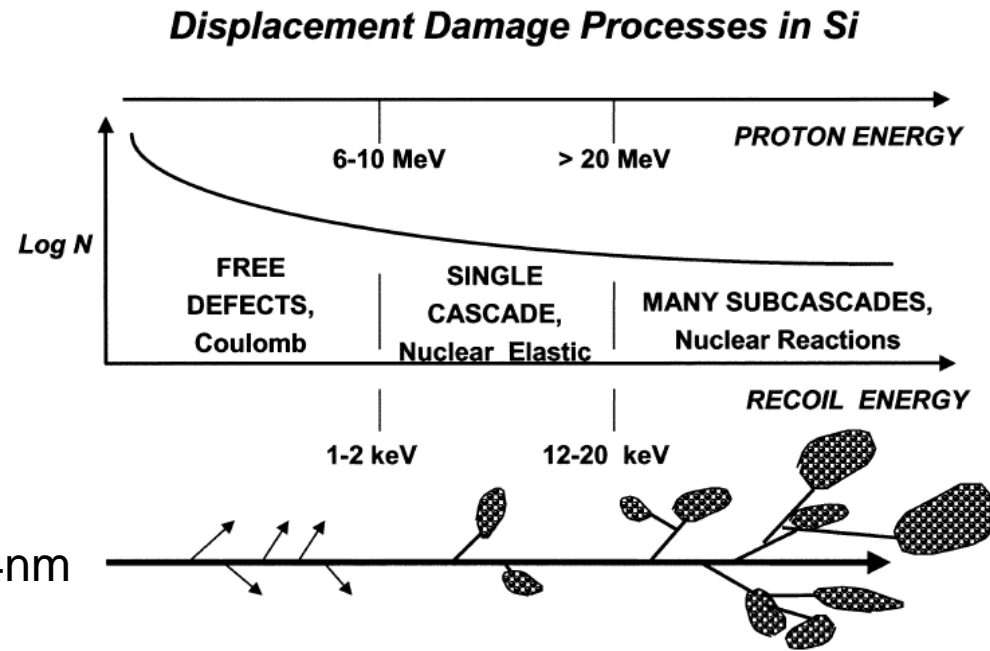
*MC = Monte Carlo (Binary Collision Approximation)
 **MD = Molecular Dynamics
 ***k-ART = Kinetic Activation-Relaxation Technique

Displacement cascade: clusters and subclusters

- Neutron 1 MeV in Silicon (Van Lint NS 1972)

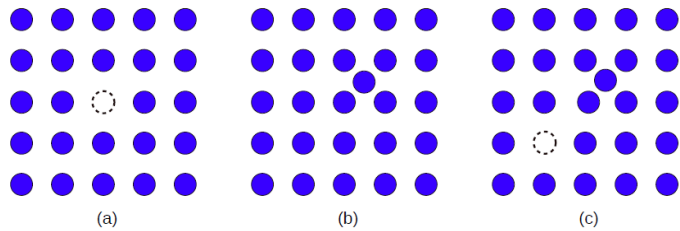


— 24nm*24nm

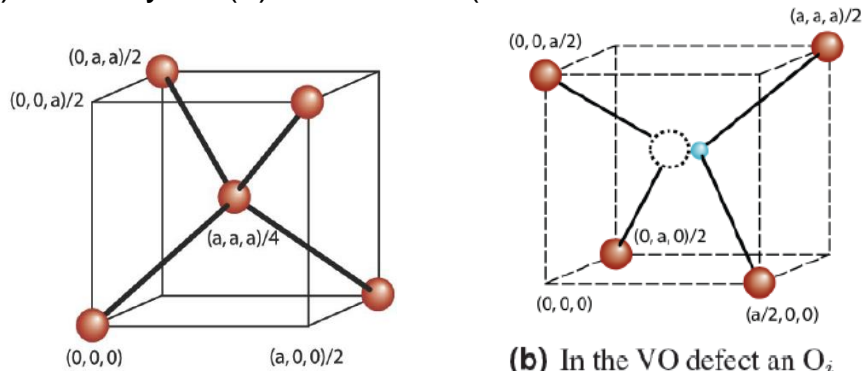


S. Wood, N. J. Doyle, J. A. Spitznagel, W. J. Choyke, R. M. More, J. N. McGruer, and R. B. Irwin, "Simulation of radiation damage in solids," *IEEE Trans. Nucl. Sci.*, vol. 28, pp. 4107-4122, Dec. 1981.

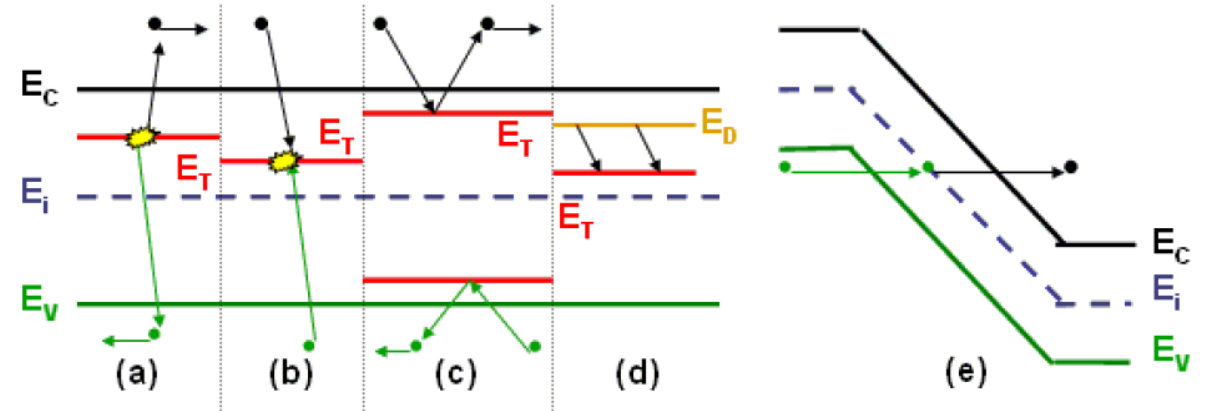
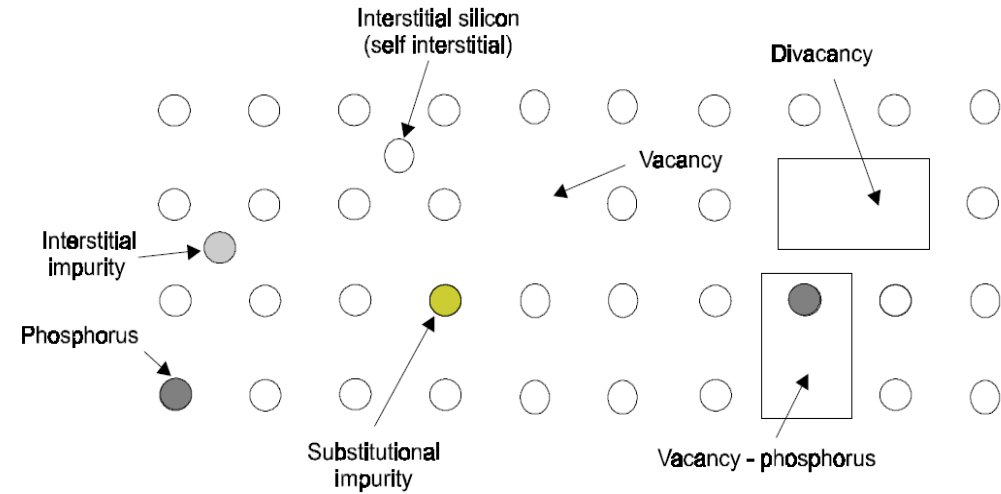
Defects structures : Frenkel Pairs, Complex defects



(a) Vacancy (b) interstitial (c) Frenkel Pair IV



(b) In the VO defect an O_i and a V share an Si substitutional site



The Target: Electronic world

From Applications, systems, circuits, elementary devices, crystals and atoms

The Different abstraction levels

Semiconductor materials

Silicon, Germanium
SiC, siGe, GaN, GaAs,
InGaAs, InP,.....
CdTe, HgCdTe

Insulators:

SiO₂ Si₃N₄ **HfO₂**

Dopants **B,P,As,..**
Silicides (Co,Ti)

Metals:

Cu, Al

Active Elementary Devices

Diodes :

PN PIN Schottky Zener LED
VCSEL

Transistors: **Bipolar BJT**,

MOS, HEMT, IGBT, JFET

Thyristors, GTO

Passive devices:

resistors, capacitors (MIM)

Power, RF, Analog

Integrated circuits

Digital: Memory, FPGA
processors, ASICS ...

Analog: Amplifiers, Ref

Voltage, comparators,

Mixed Analog-digital, smart
Power,..)

Optronics

SOC

3D Integration

Subsystems
Systems
MegaSystems

S

A

G

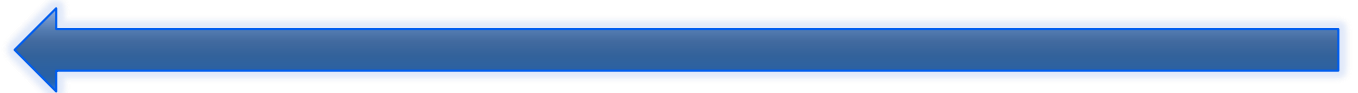
A



RADSAGA



RADECS 2017
CERN, Geneva



Multi abstraction Levels in Simulation and modeling electronics: from atoms to system

- **Atomic level modeling:** detailed atomic structures.
- *Numerically Solving Schrodinger's equation using Hartree-Fock (HF) or Density Functional Theory (DFT)*
- **Technology level modeling**
- layer structures, doping profiles, resulting electrical characteristics.
- *numerically solving process and transport differential equations for a single transistor. (TCAD)*
- **Device level modeling :** description of transistor terminal characteristics expressed in compact closed-form equations. (SPICE)
- **System Level Modeling and EDA tools** description and synthesis of global functions
- *Each level of abstraction outputs are inputs to the following level of abstraction*

Radiation effects: how to classify?

Bulk defects: **Displacement Damage (NIEL)**

- Carrier-generation and recombination GR
- Density of carriers (for high resistivity material)
- Leakage current (related to Generation by defects)
- Mobility of carriers (defects diffuse free carriers)

Trapped charges in insulators and at SC-Insulator Interface (**IEL-TID**)

- Modify threshold voltage of MOS devices
- Induce inversion channels and leakage between devices
- Induce noise

Hole-electron pairs in Semiconductors (**IEL**)

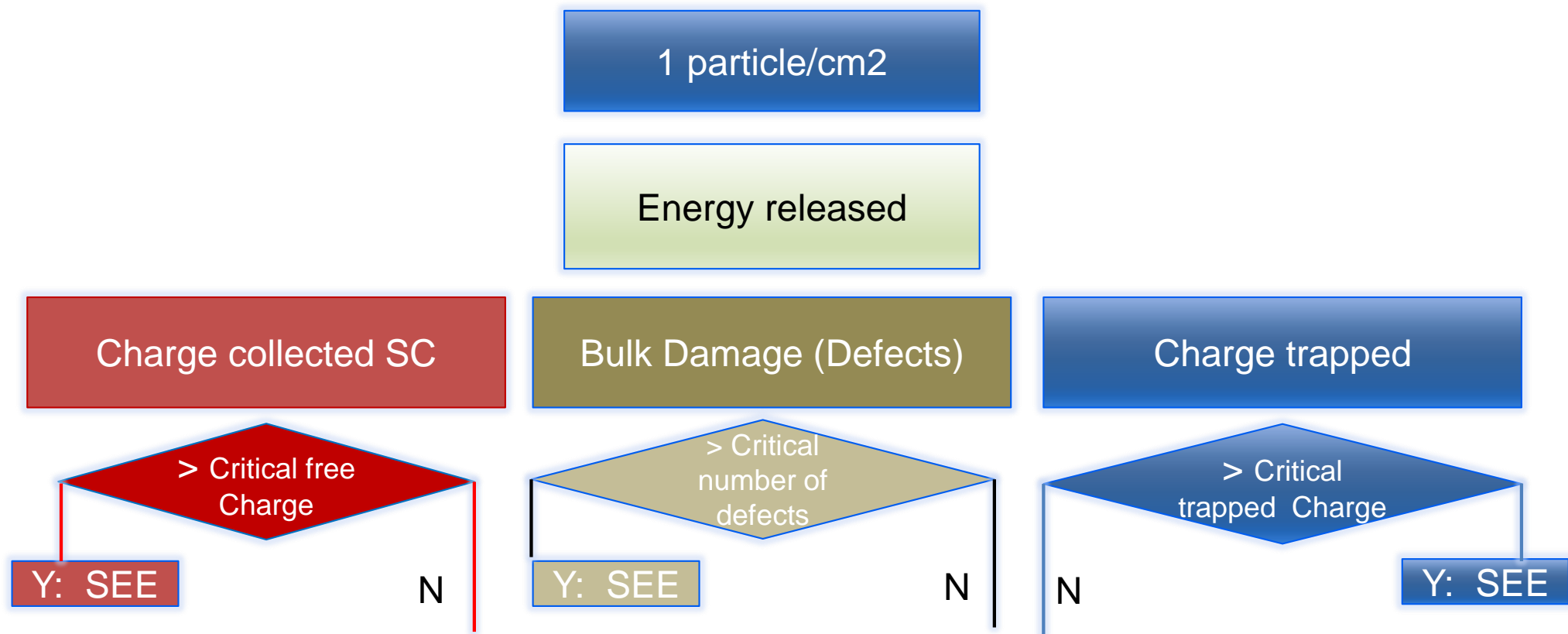
- Transient currents

Cumulative Effects

- The observed effects increase when the number of impinging particles increases
- The effects are mostly stable at the time scale of the irradiation
- Some annealing may exist
- Failure will appear for a given fluence ($\int_0^t Flux dt$)

Single Event Effects

- Effect produced by **One** incident particle
- **Events may appear as soon as irradiation begins.** Frequency of events is proportional to the flux of particles



Is time separating 2 impacts > Time duration of Effect?

Y: No Effect

N: Cumulative Effects

Electronic circuits and reliability

- The reliability is a main concern and different parameters are defined
 - MTBF : mean time between failure (for recoverable of soft errors)
 - MTTF : mean time to failure for a destructive effect
- FIT (Failure in Time)
 - 1 FIT = one failure for 1 E9 hours,
 - →1FIT = 1 failure for 1.14 E5 years!!!
- System FIT = $\sum_{i=1}^n FIT(i)$
- FIT value is related to a particular environment: At Ground level JESD89A Standard
- Reliability is related to external and internal environments and device sensitivity to these environments (Temperature, Humidity, Vibrations, Radiation, Aging)
- Radiation must be considered if the global FIT value is significantly increased by radiation

Example of Electronic systems: Titan Supercomputer - modular structure

1 node= CPU 16 core Opteron 6274 32GB DDR3,
NVIDIA GPU K20X Kepler 6GB DDR5, Router

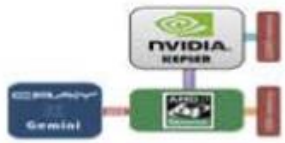
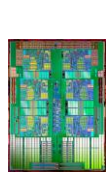
1 Blade= 4 nodes

1 Cage= 8 blades

1 cabinet =3 Cages

TITAN=200 cabinets

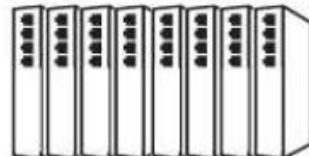
= $4 \times 8 \times 3 \times 200$ nodes = 19200 nodes



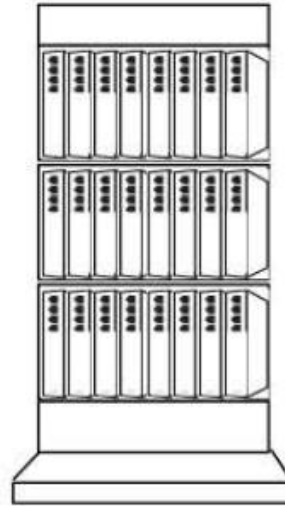
Compute Node



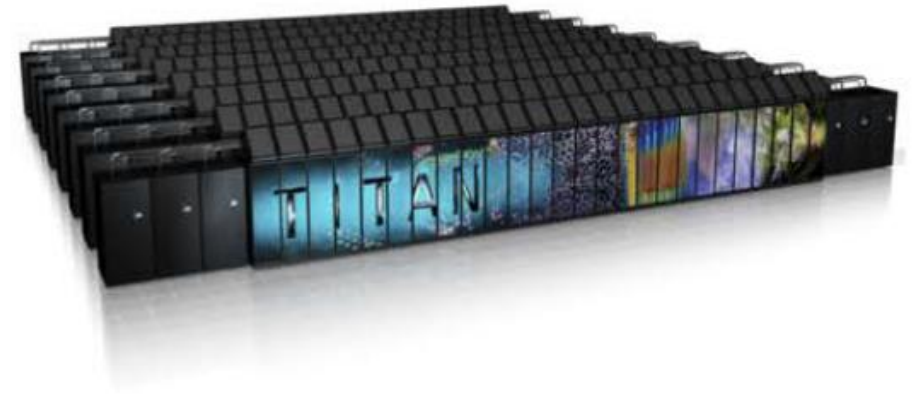
Blade



Cage



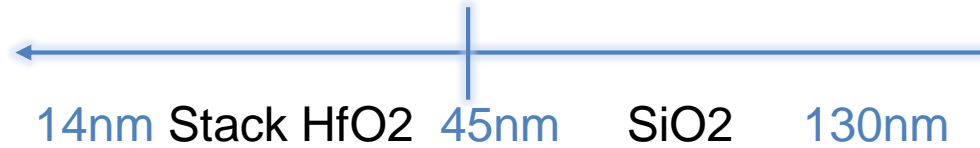
Cabinet



200 Cabinets (25 rows x 8 columns)

Insulators in Integrated Circuits

- Gate of MOSFET **EOT**



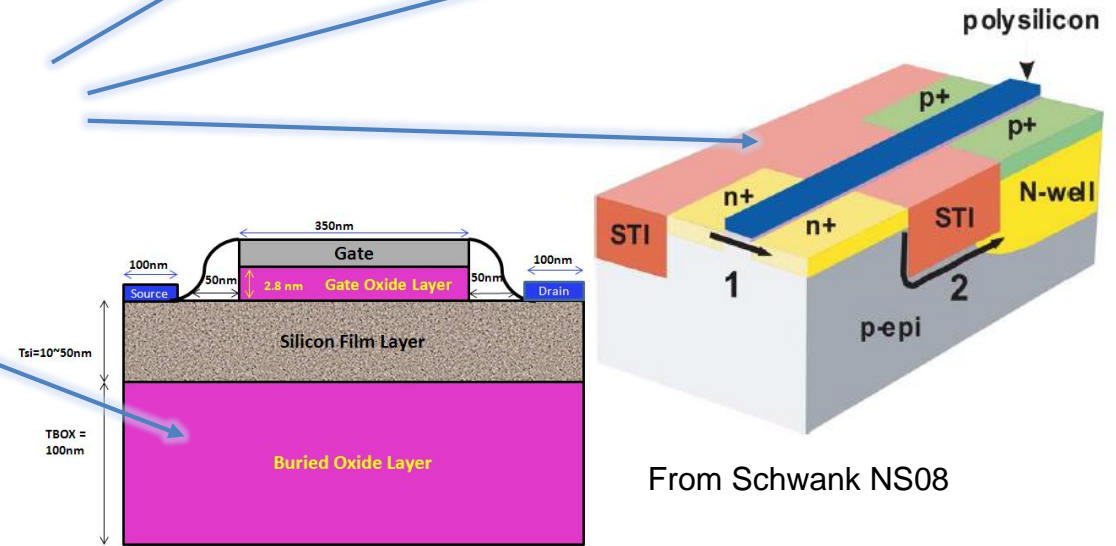
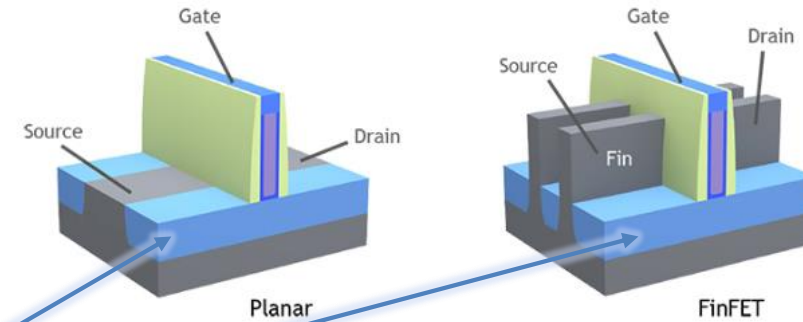
- Isolation between devices STI

- BOX (Buried Oxide) in SOI

- Passivation of bipolar devices

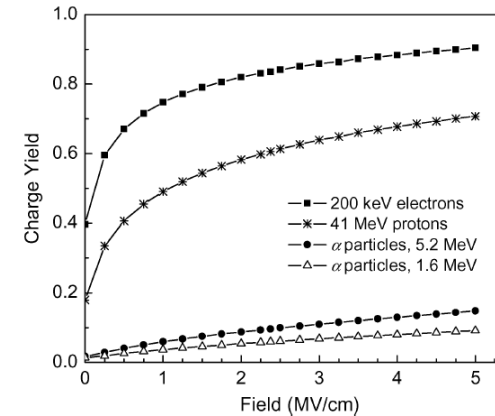
- Inter-metal levels separation

- Low k dielectric

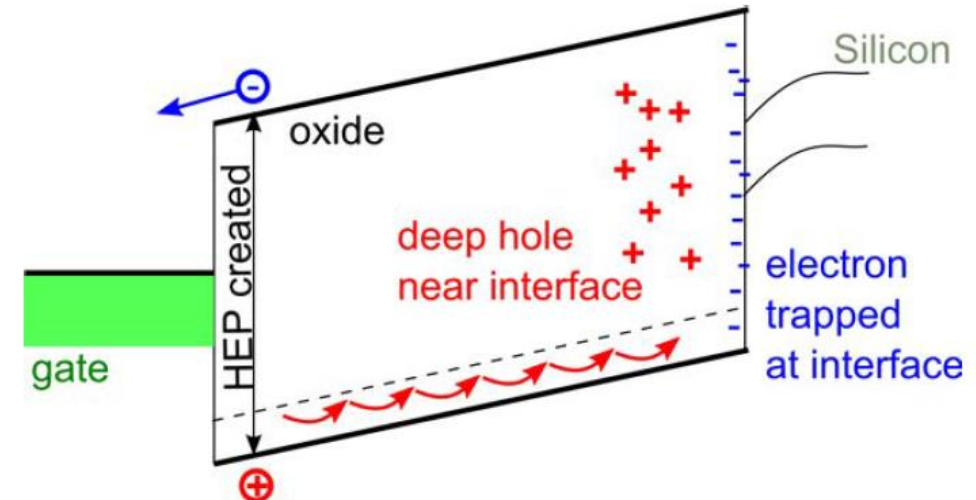


Total dose mechanisms: Trapped charge in insulators

- Ionisation (Creation of Hole-electron pairs) $E_p=17\text{eV}$ in SiO_2
- Recombination in ionised column (geminate or columnar),
- Separation of carriers $e^- h^+$ by Electric Field (yield).
- Fast Evacuation of e^- (high mobility)
- Slow transport of holes (hopping, Multiple-Trapping-Detrapping in shallow traps)
- Trapping in deep traps
- Compensation by electrons tunnelling from Si

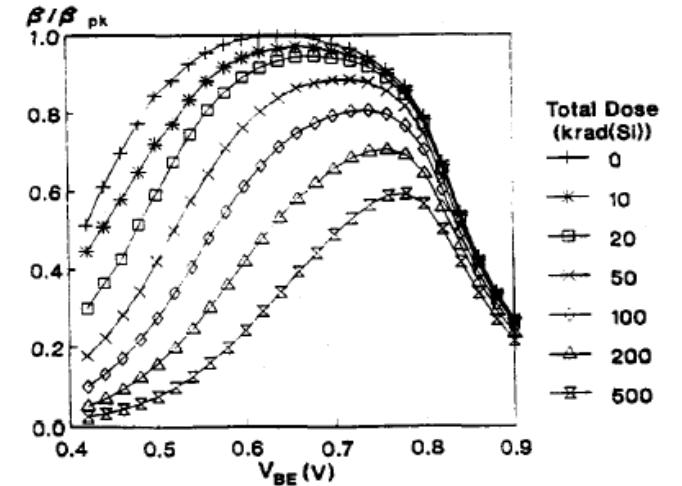
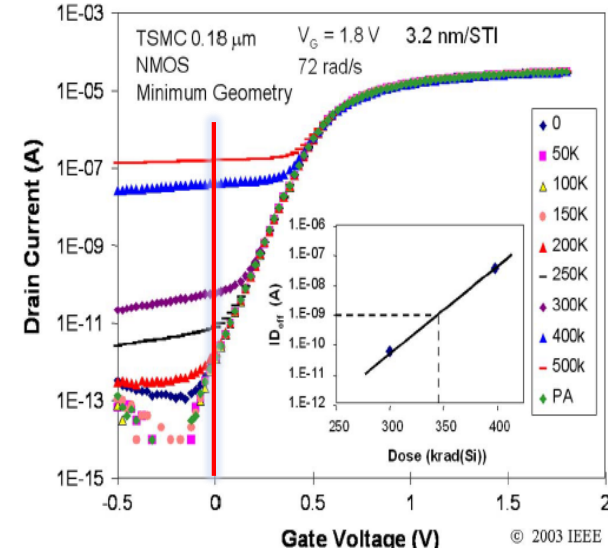


Yield is a function of the Electric Field and of the incident particle (e^- , X-Ray, p , ion)



TID Effects

- MOS Transistors:
 - Negative Shift of threshold voltage NMOS easier to turn ON, PMOS more difficult to turn ON
 - Decrease of subthreshold slope for NMOS, leakage current at $V_{GS}=0V$
- PN junction: inverse current
- Bipolar transistor: gain
- Integrated circuits: static power supply current



TID: Influence of Dose rate

For CMOS worst case is obtained at high dose rate.

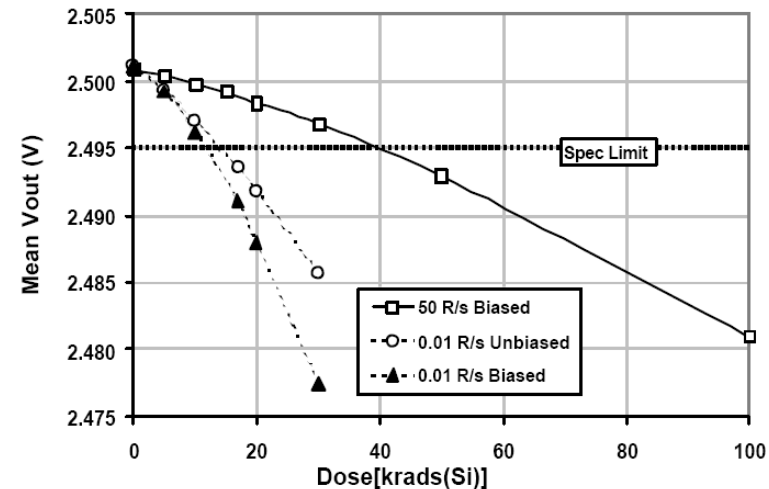
Experimental Test simulates **years** of life by a **week** or less of irradiation followed by **annealing** at room temperature or high temperature.

ELDRS (Enhanced low dose rate sensitivity) in some bipolar devices is a **challenge for testing**.

LT1019 Reference Voltage

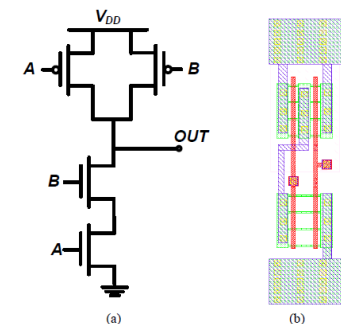
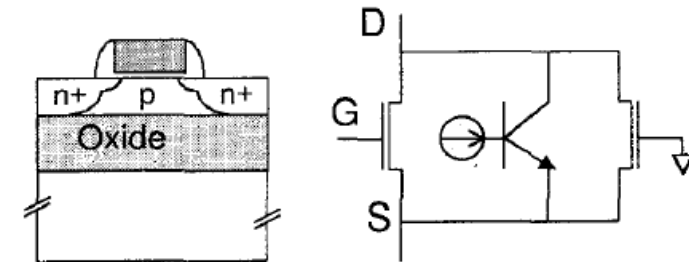
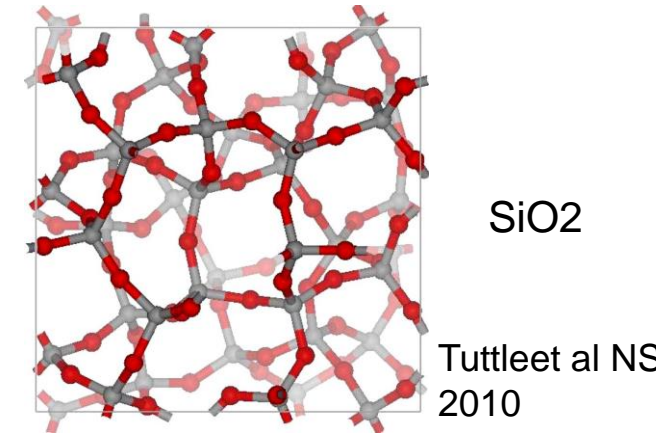
0.01 Rad/s: 36rad/h

100krad → 116 Days of irradiation



Simulation of TID effects

- Insulator: **Atom level** description of traps and interface states, charge transport, trapping, annealing,
- Devices: **TCAD**, Variation of electrical parameters
 - MOS: (V_{Th} , leakage, transconductance)
 - Bipolar: Gain at low current, Emitter-collector leakage
- Inter-devices leakage
- Gates, complex circuits: **SPICE** : Power supply current, dynamic parameters (T_r , T_f , T_d), functional failure
- System?



Single Event Effects

Effects related to the interaction of a single particle

Ionization in Insulator

- Trapping of charges in Deep Traps
- SHE (Single hard error)
- Microdose effects

Displacement Damage in Semiconductor

- Recombination-Generation-Centers (SRH)
- Dark Current (CCD, APS)
- Leakage current (Junction)
- SDRAM stuck bits
- Gain degradation in BJT

- **Ionization in Semiconductors**
 - Heavy Ions, Protons, Recoils, *Muons, electrons*
- **Drift and Diffusion of free carriers**
 - Collection at Junction contacts
 - Charge sharing between contacts
- **Trigger of non destructive effects**
 - SET (Single Event Transient)
 - SEU (Single Event Upset)
- **Trigger of Destructive Mechanisms**
 - SEL (PNPN structures in CMOS bulk)
 - SEB SEGR (Power MOST, IGBT)

Single Particle: Charge carrier Generation (IEL)

- **Generation: Tools Geant4 SRIM**

- Energy loss per unit length: dE/dx
- LET (Linear Energy Transfer)
- Unit of LET: $\text{MeV}/(\text{mg}/\text{cm}^2)$ (Practical unit to get values from 1 to 100)
 - when charge generation is considered : $\text{pC}/\mu\text{m}$
 - For silicon: $d=2.33\text{g}/\text{cm}^3$, $E_p=3.6\text{ eV}$, $1\mu\text{m}\rightarrow 0.233\text{mg}$ $q=1.610^{-19}\text{ C}$

Result: $1\text{pC}/\mu\text{m} \rightarrow 97\text{ MeV}\cdot\text{cm}^2/\text{mg}$

Generation and available electrons in valence band:

Silicon $Z=14$ $A=28$ $2.33\text{g}/\text{cm}^3$ M layer $2\text{ E}^{23}\text{e}^-/\text{cm}^3$

Charge Density : track radius 10nm , LET: $1\text{pC}/\mu\text{m}$ density: $2\text{ E}^{22}\text{ e}^-/\text{cm}^3$ 10% ionized

Avogadro	6,02E+23
Mass	28g
	2,33g/cm ³
Volume	12,02cm ³
Density	5,01E+22 Atoms/cm ³
available electrons	
=4*	2,00E+23 electrons/cm ³
	Density of Silicon atoms
	Available electrons in Valence band

Collection and Models of Current Transients

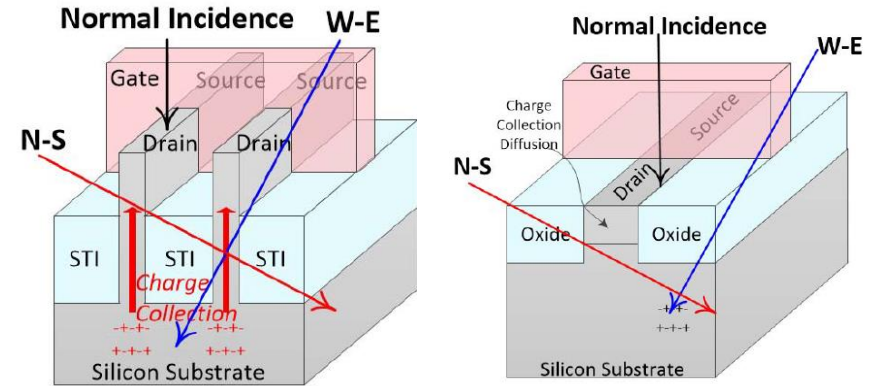
Collection of Charges : TCAD 3D

Generation across a space charge layer:

Electric Field E

Drift of carriers $v=\mu E$ or $v= v_{lim}$

Modification of Electric Field



Generation in neutral region:

Ambipolar diffusion : high density of carriers (>majority carriers)

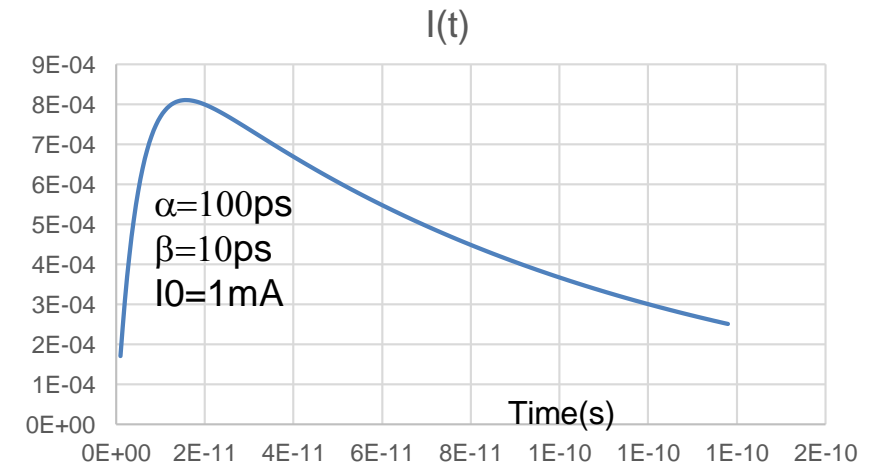
Cohesion of the track maintained by lateral electric field

Collection: Diffusion to junction and contacts

➔ **Transient current**

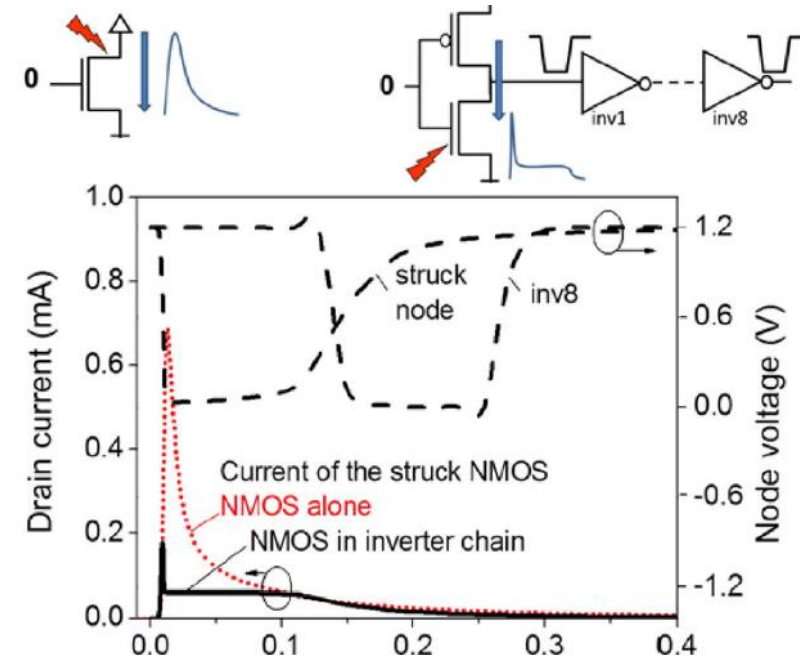
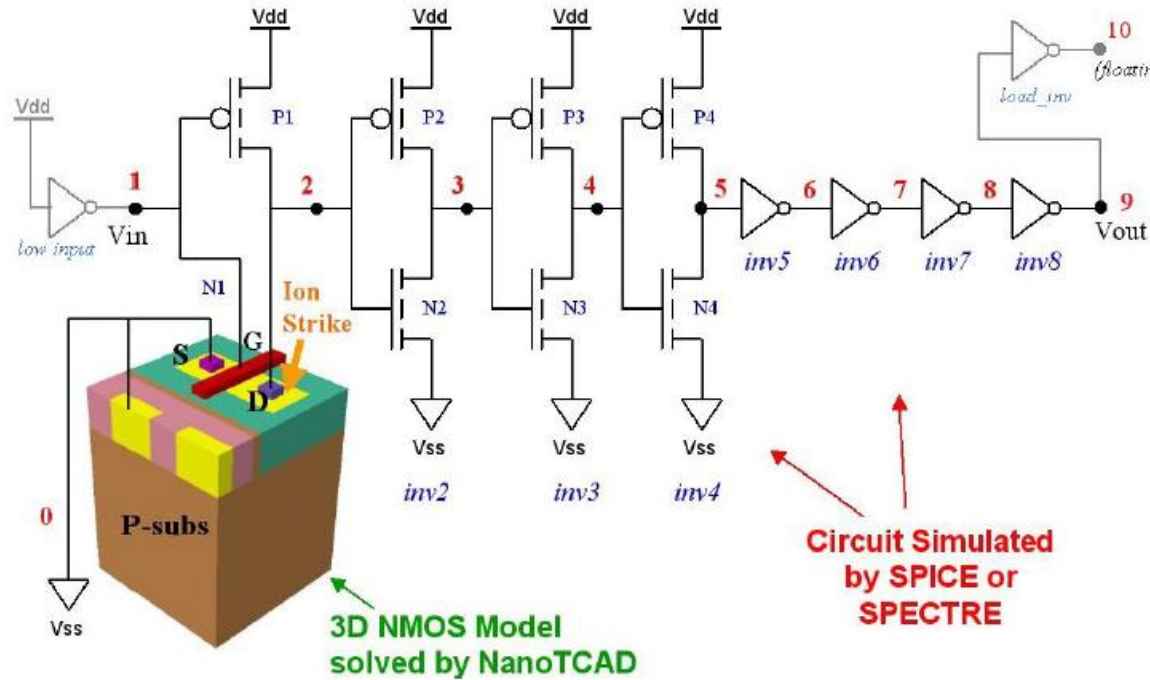
Orders of magnitude: $Q_{collected}=1pC$, $T=1ns$ $I_{peak}=Qc/T=1mA$

Simple analytic formula $I(t)=I_0 (\exp(-t/\alpha)-\exp(-t/\beta))$
 β : time constant to establish the generation
 α : collection time



SET in digital circuits (DSET) Propagation

Review: V. Ferlet-Cavrois et al NS 2013)



SEU: Single Event Upset

- Change of state ($0 \rightarrow 1$, $1 \rightarrow 0$) of the output of a latch, Flip-Flop, SRAM cell... due to an impact in an elementary device (MOST, BJT)
 - In bulk CMOS Drain junctions of Off Transistors (Drain-substrate or Drain Well) are the most sensitive nodes

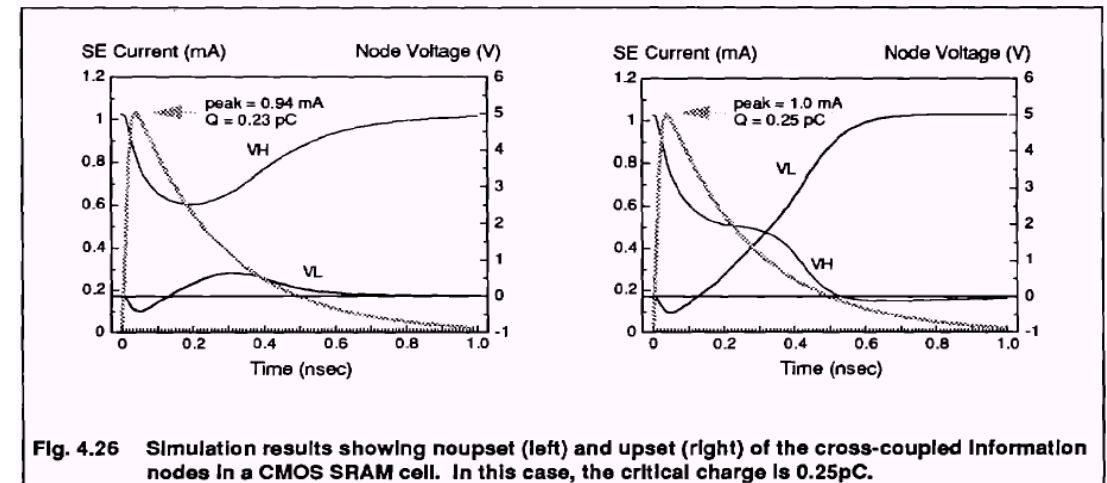
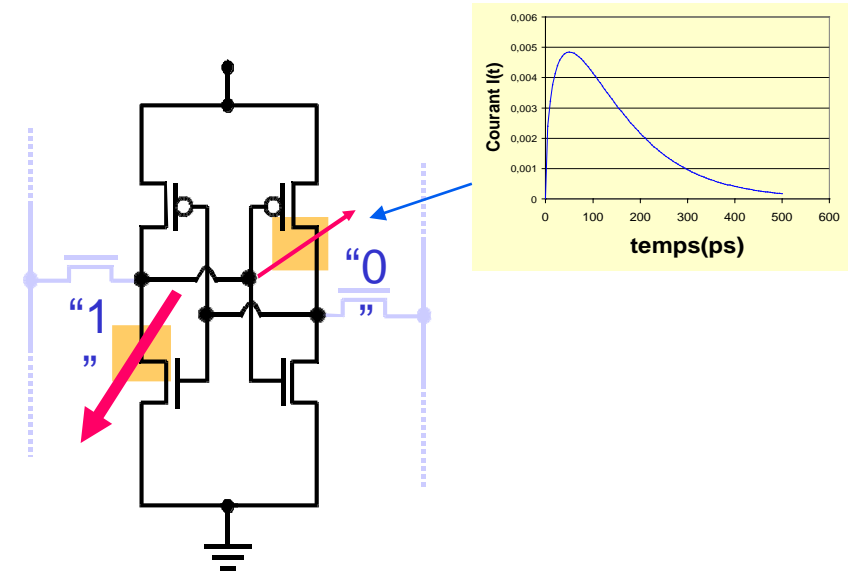
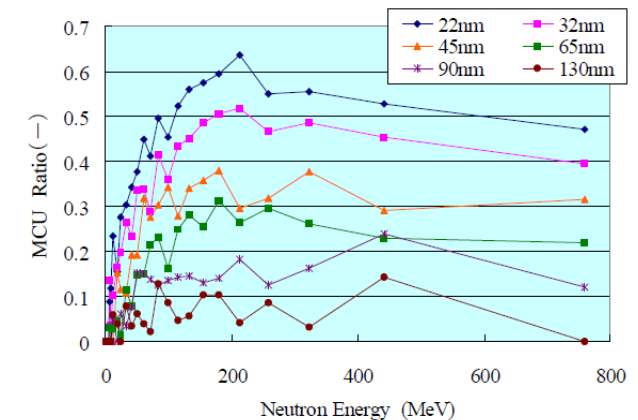
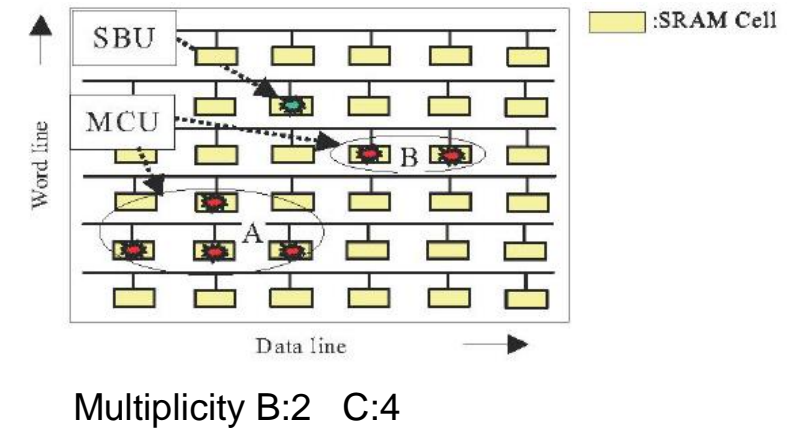


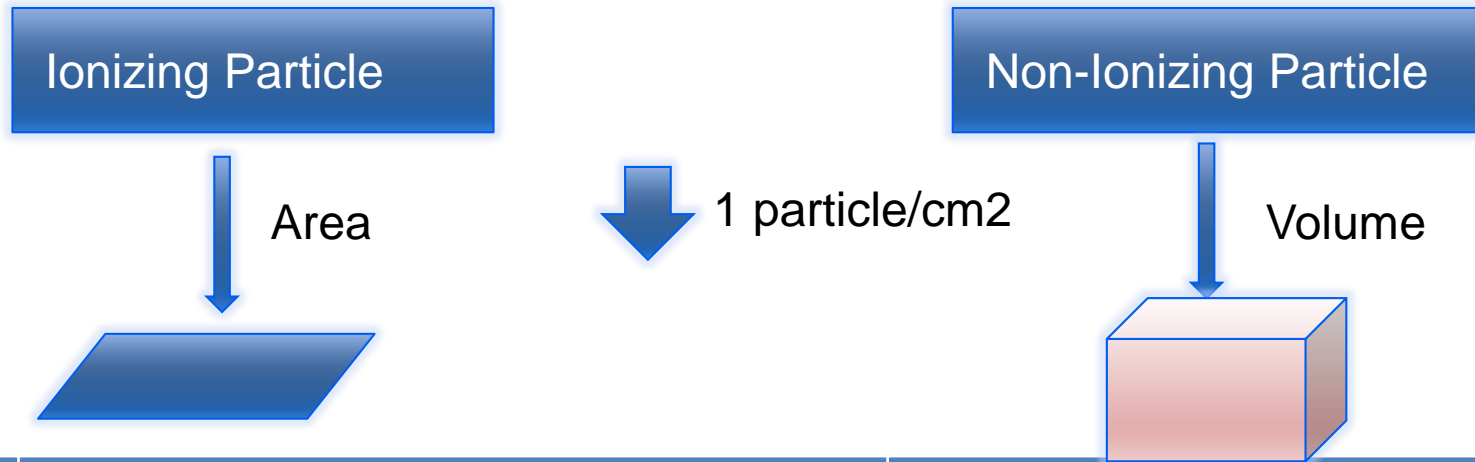
Fig. 4.26 Simulation results showing noupset (left) and upset (right) of the cross-coupled information nodes in a CMOS SRAM cell. In this case, the critical charge is 0.25pC.

MCU: Multi Cell Upsets

- Jedec: « A single event that induces several bits in an IC to fail at the same time. NOTE: The error bits are usually, but not always, physically adjacent”.
- MCU/SEU ratio increases when technology node decreases (R=0.1 at 130nm, R=0.5 at 32nm)
- Multiplicity increases
- Problem for ECC (Hamming Code: Detect 2 correct 1)
- Scrambling of bits in same word (MCU but not MBU)



Single Event cross-section



Dimensions	Probability (to cross-area)	Probability of interaction in Volume ($\sigma=1\text{barn/atom} = 1 \text{ E-24cm}^2\text{/atom}$)
1 μm *1 μm	1 E-8	5 E-14
100nm*100nm	1 E-10	5 E-16

Saturated cross-Section /bit:

HI

neutrons



RADSAGA



RADECS 2017
CERN, Geneva

Potentially destructive Effects: Single Event Latchup

- **Parasitic** structures in CMOS bulk
- Trigger of a PNP Thyristor parasitic structure switching from Off-state to ON-state
- Condition of SEL:
 - *Existence* of PNP Structure (SOI SEL free)
 - *Activity* of the Structure (influence of Wells Contact density on R_p R_n)
 - *Minimum bias voltage* $> V_{hold}$
 - *Available current* $> I_{hold}$
 - More important at high temperature (gain of bipolar transistors increases)

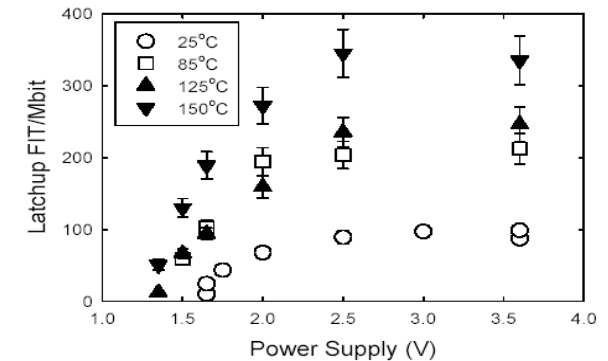
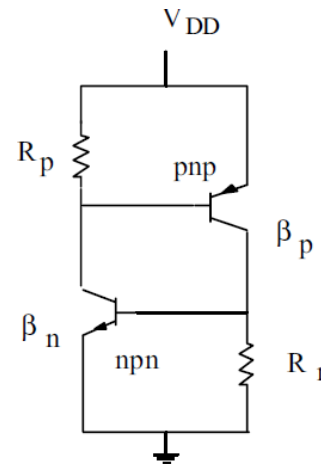
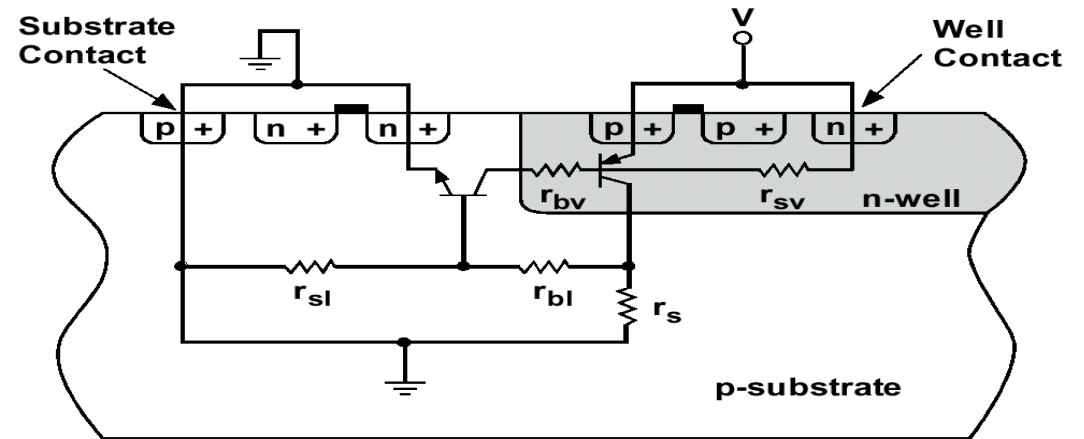


Figure 5. Neutron-induced latchup rate in 3.3-V SRAMs from Vendor B as a function of power supply voltage and operating temperature.

Destructive Effects: Power MOST and IGBT

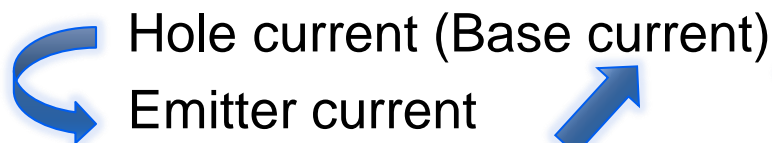
SEB: Single Event Burnout

Parasitic NPN transistor (normal state: blocked) is switched ON.
 Electrical Field profile modified by current in space charge layer

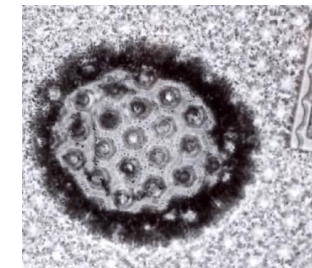
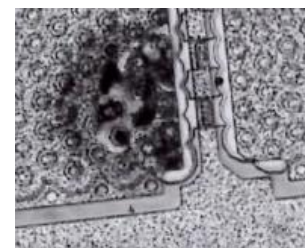
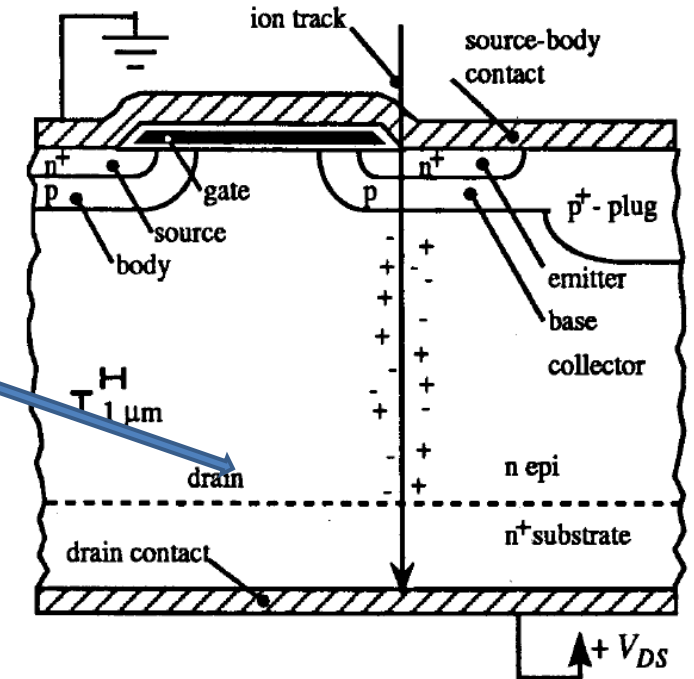
Electric Field z extension limited to NN+ homojunction

Peak electric field

Carrier multiplication at critical Efield



Local Heating and localised burnout



IRF240
 VDS=190V HI

Parasitic structures-Mitigation

- Parasitic structures inherent to the process may influence strongly the radiation response. **Some technological mitigation is possible.**
- NPN parasitic structure in Power MOST: SEB
 - **Modify the NN+ doping profile to extend the E field zone and limit Epeak**
 - **Reduce the Rbe resistor value (increase doping, modify thickness,...**
- PNP structure in CMOS bulk : SEL
 - **suppress the structure (SOI),**
 - **reduce Rn, Rp values**
 - **Reduce gain of BJT (doping profile, deeper STI for lateral BJT,.....**
- SOI: open base parasitic bipolar transistor
 - **Add body ties**

Hierarchy of priority of REE to be solved

(Atmel, GlobalTCAD, Project Desmicrex)

Requirement for Radiation Effects Analysis and Priority

1. *Single event latch-up*
 - *Effects of angle, impact position, temperature*
2. *Single event transients / DSETs + Multiple Transients*
 - *Effects of angle, position, clock-freq, cross-talk, temperature*
3. *Single event upsets / multiple-cell upsets*
 - *Effects of angle, position, temperature*
4. *Single event hard error (stuck bits)*
5. *Total ionising dose*
 - *Intra- and inter-device leakage across STI*
6. *Dose enhancement effects*
 - *Use of Cu and other high-Z materials*



Decreasing
priority

Radiation Hardening: To improve performance under irradiation

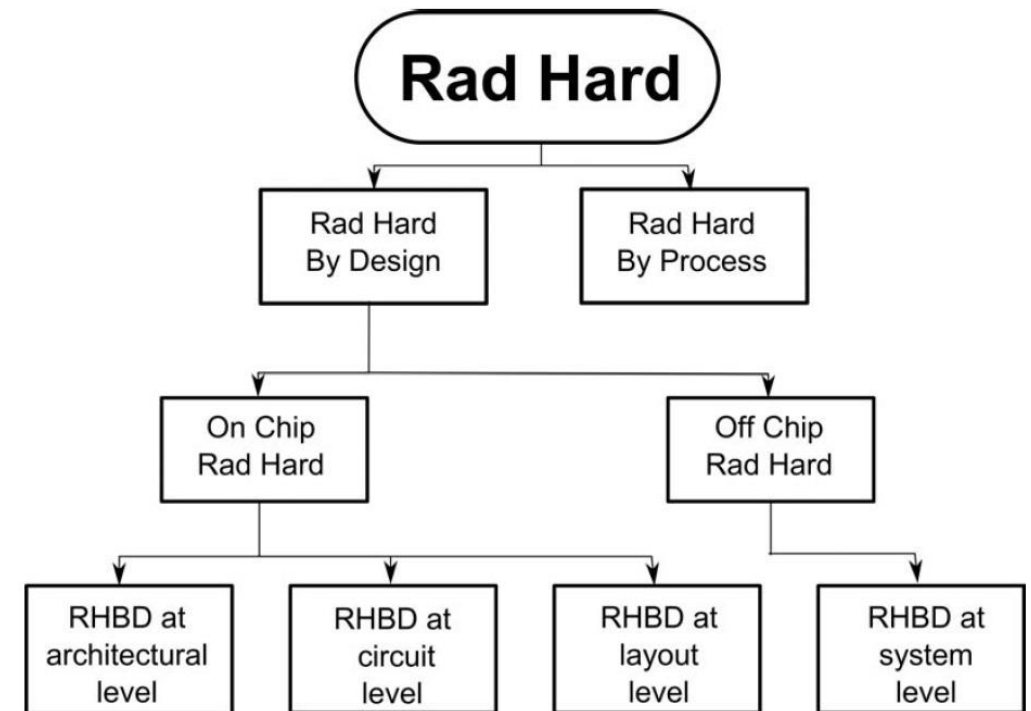
Radiation Hardening by Process: (RHBP)

Identify the mechanism of failure and its relation with a process step. Examples:

- thermal treatment of oxides: limit density of traps
- Limit or suppress 10B (SEU by thermal neutrons)
- Limit oxygen content in silicon (V-O recombination center)

Radiation hardened by design (RHBD)

- Circuit level hardening (feedback loops)
- Architectural level hardening (TMR)
- Layout considerations (guard rings, closed NMOS)



Specifications of Radiation environment

- Radiation environment is given in specific units related to the effects considered
 - TID: deposited energy
 - RAD: Radiation Absorbed Dose = 1 E-5 J/g GRAY: (Gy) $1 \text{ Gy} = 1 \text{ J/kg} = 100 \text{ rad}$
 - Dose relative only to a given material Gy(Si), Gy(SiO₂)
 - Knowledge of Origin and energy spectrum is lost
 - LET can be converted to dose in rad
 - DD: Fluence (particles/cm²)
 - 1 MeV neutron Equivalent Fluence (NIEL)
 - SEE: Flux (particles/(cm²*s))
 - Heavy Ions : LET spectrum, Flux
 - Hadrons: Flux ($E > E_0$) or differential Flux (dn/dE)
 - Thermal neutrons (25meV equivalent)

Radiation Effects Testing: Reproduce the effects but not the real environment

TID : Co60, electrons, protons

Parameters: Dose rate, Electrical bias, temperature, dynamic or static

- *Identify worst case conditions*

On line measurements

Off-line (irradiation steps):

Two different approaches are needed for preliminary characterisation and qualification (follow standards ESA and MIL Std 883 Method 1019)

DD: Fluence expressed in 1 MeV-neutrons equivalent

Electrical conditions not important

Low annealing after defect stabilisation

Neutron reactors (E<6MeV),
neutrons generators (14 MeV)

(DD+TID)

Proton beams

Mixed beams

Importance of initial measurements and choice of samples (mean values of the population, no maverick) with a sufficient number (dispersion in a Lot and between different Lots)

Single event effects testing : Facilities

Heavy ions: (UCL, RADEF, Tamu,..)

- Flux variation
- LET values, HI Range

Proton:

- Energy and Flux
- Beam area, Flux uniformity

Neutrons:

- monoenergetic (D-T 14 MeV, D-D 2.3 MeV)
- quasi-monoenergetic (UCL)
- broad spectrum (Lansce, Anita,...)

Mixed environment (Charm)



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Microbeams (spatial localisation)

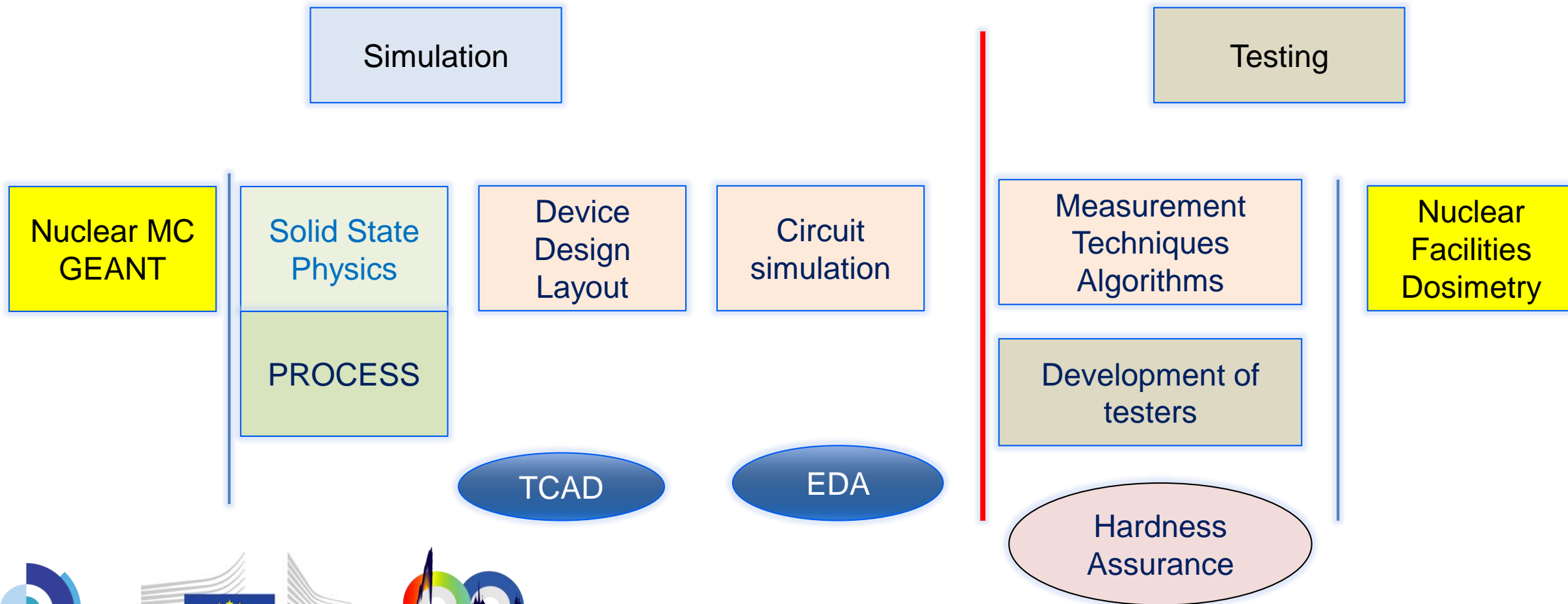
Laser Testing (ps duration, focused, single shot or pulse rate)

- *Spatial Localisation*: identify sensitive zones, X-Y scanning
- *Temporal Localisation*: Possible synchronisation with electrical signals
- **No Metallisation penetration** (backward testing)

X-Ray focused ps Pulse

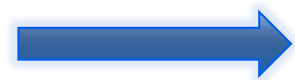
- A solution to metal penetration ?

REE: SKILLS



Drivers for Research and studies on REE

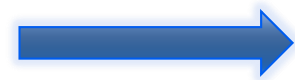
Failures in applications



Task Force

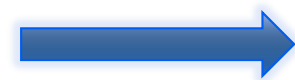
SEE, DD in low earth orbits, Memory bit-flip in avionics, SEL in automotive, SEE at ground level: Routers, Computers : Radioactive contamination:

Obsolescence



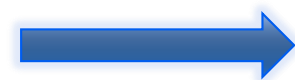
Need for new devices: sensors,..

Anticipation of new Effects



Moore Law, Shrinking: p direct ionization, SEE e, μ , 3D technology

New Needs
New Systems
High Radiation



Power (SiC, GaN) Frequency (HEMT), Robotics

Test facilities

Simulation tools

COTS Hardness Assurance



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European Commission



RADECS 2017
CERN, Geneva

Radiation Effects on Electronics community (RADECS, NSREC) and other scientific communities

- Radiation and reliability: IRPS (International Reliability Physics Symposium)
- Radiation and testing methods (IOLTS)
- Radiation and electronic circuits design (VLSI)
- Specialized conferences : (see IEEE)
- Useful to meet other communities and apply some of their methods and models
 - Environment (Radioactivity, cosmic rays, Radon, IAEA,
 - Physics (nuclear, solid-state, semiconductor and insulators)
 - Electronics (technology, TCAD, EDA, circuit design, simulation and testing)
 - Accelerators, Reactors, dosimetry

Conclusion

- Radiation Effects on Electronics is a **mature field of research**
- New studies are much more efficient than in the past with the strong benefice of methodology and tools developed for Electronic Industry. **Virtual simulation from ab initio to system modeling helps to understand and predict effects.**
- But there exist still a need to reinforce this community in order to take into account the different problematics (space, atmosphere, ground, nuclear energy, medical and even military), to improve simulation tools and to develop industrial standards for testing and qualifying.
- A **driving force is semiconductor technology** with a broad spectrum of **high reliability applications at ground level** that takes radiation effects into account

There is much room for working on Radiation Effects on Electronics in research and industry and to find pleasure and satisfaction in this work.

Useful Lectures (only a few references, much more available)

- Defects in Materials and Devices Microelectronic
 - Edited by Daniel M. Fleetwood, Sokrates T. Pantelides, Ronald D. Schrimpf
- Ionizing Radiation Effects in MOS devices and circuits
 - T. P. Ma P. V. Dressendorfer
- Reliability and Radiation Effects in compound semiconductors
 - A. Johnston
- Soft Errors From particles to circuits
 - J.L Autran and D. munteanu
- The Effects of Radiation on electronic systems
 - G.C Messenger
- Physics of semiconductor devices
 - S. M. SZE

Acknowledgments

- Many thanks are due to REE Cern team that share some of their research work and invited me to give this talk.
- Many Thanks to Prof Paul Leroux and Dr Ruben Garcia Alia for reviewing the presentation
- Many thanks to you that attend this talk early in the morning before an important conference day.
- All comments and questions are welcome:

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Additional slides



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